

## PATENT ABSTRACTS OF JAPAN

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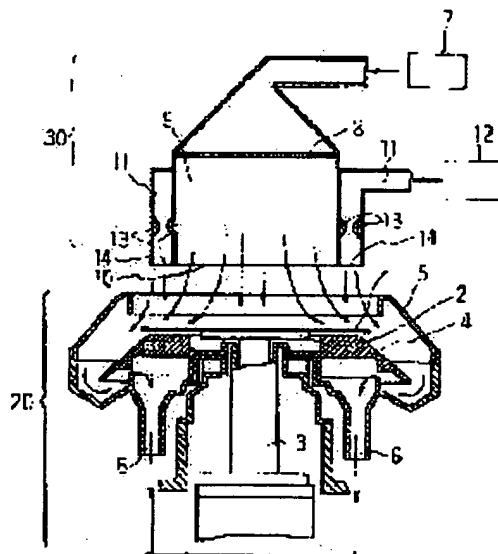
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## (54) SPIN COATING METHOD

## (57)Abstract:

PURPOSE: To form an even film by supplying a substrate with the air current so controlled that the temperature and humidity are different for each area divided along the rotational radial direction of the substrate.

CONSTRUCTION: An air current supply duct device 30 is provided with a cylindrical central part air current supply duct 9 which supplies around the central part on the surface of a wafer 1 with air current and a peripheral part air current supply duct 11 which supplies around the peripheral part on the surface of the wafer 1 with air current. The respective air current so controlled that the temperature and humidity are different is supplied to the wafer 1 from the central part air current supply duct 9 and the peripheral part air current supply duct 11 for forming a film of even thickness.



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